

Engineered Ge substrates for new power-hungry space applications
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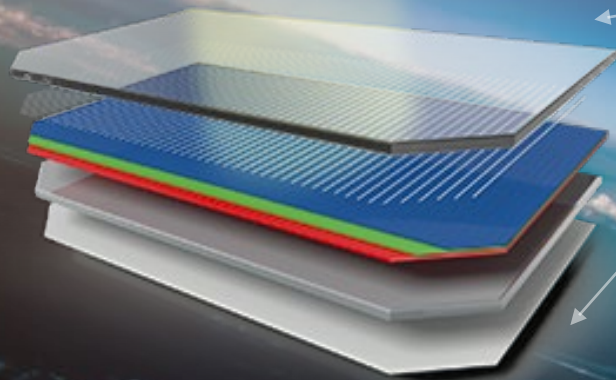


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S. Janz

Introduction

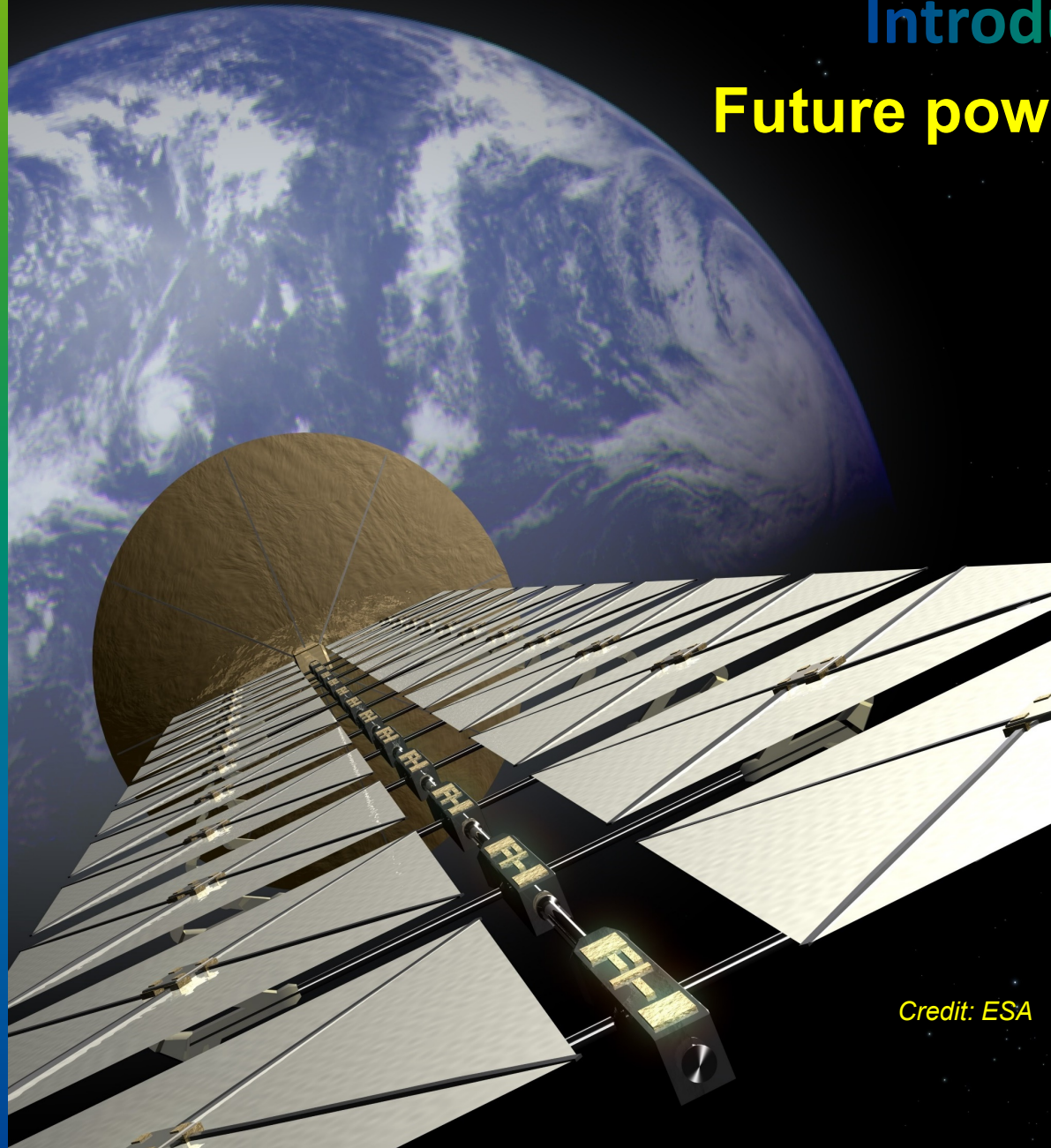
Incubent technology

GaInP
GaAs
Germanium

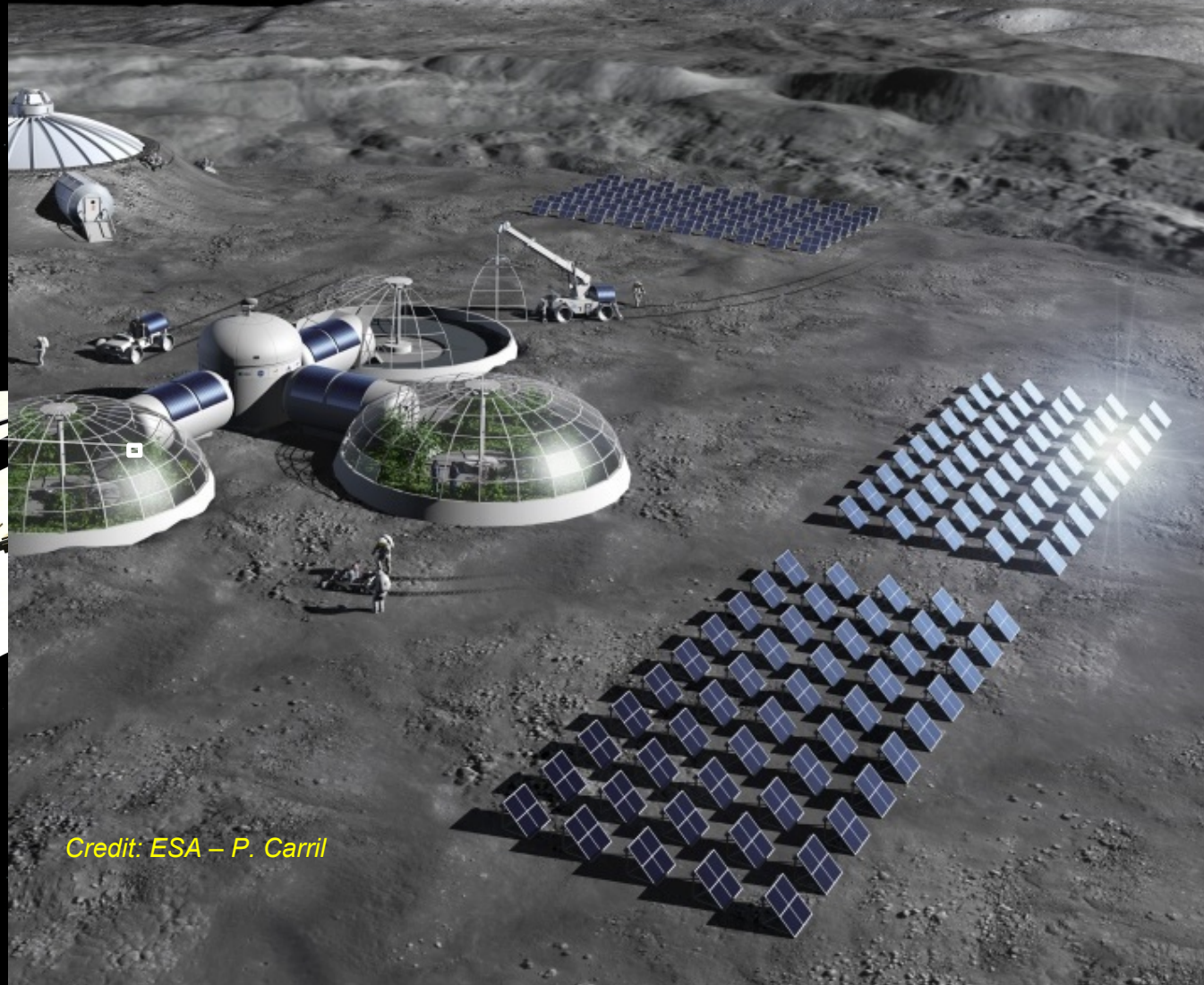


Introduction

Future power demand



Credit: ESA



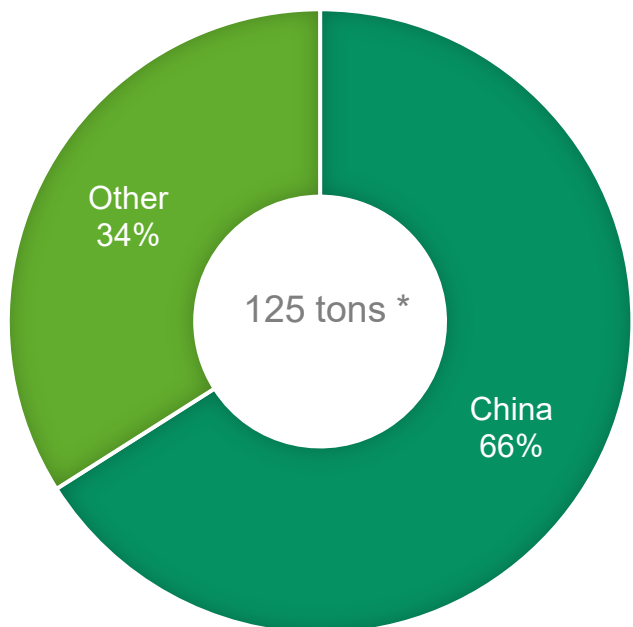
Credit: ESA – P. Carril



Introduction

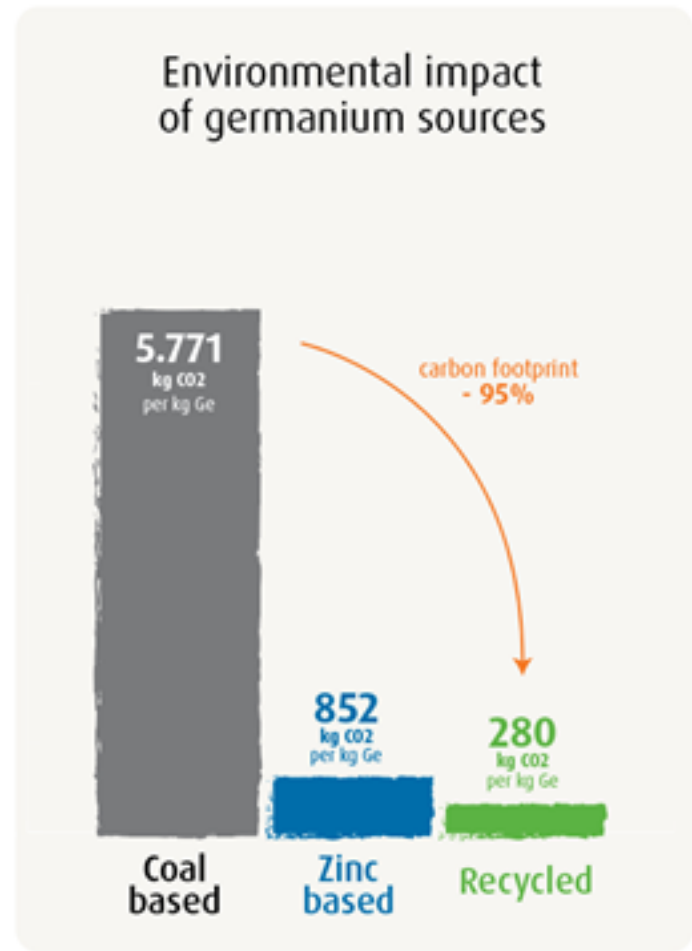
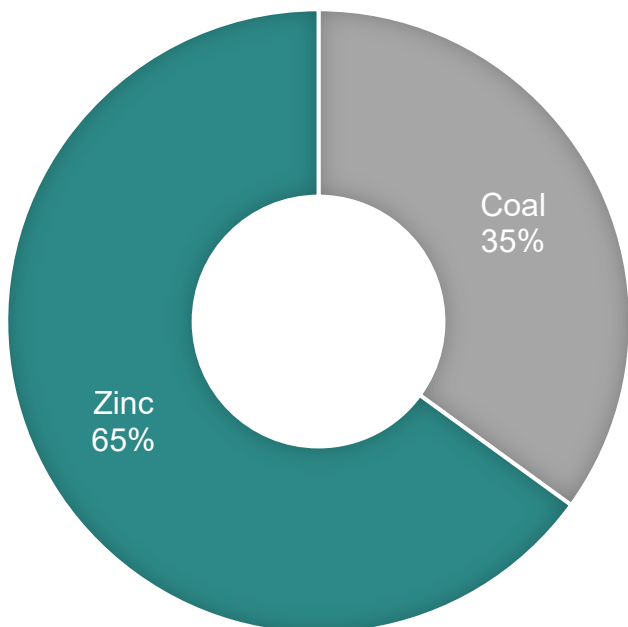
Ge is significant cost driver

COUNTRY OF ORIGIN



* Annual fluctuations are in the order of ± 15%

SOURCE TYPE

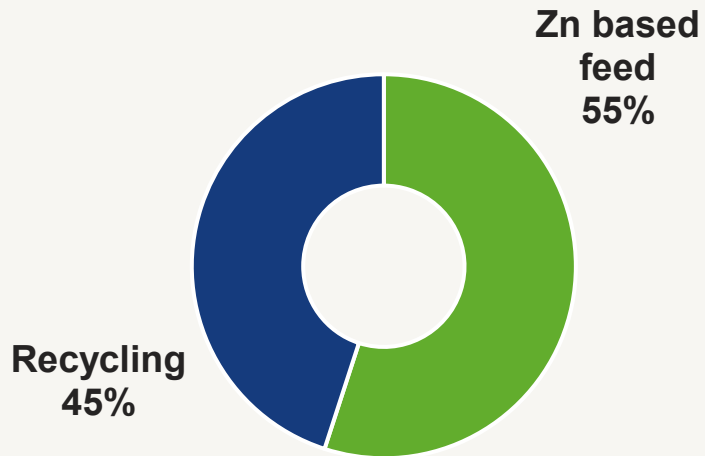


Introduction

Sustainable Ge from Umicore



EOM Primary vs Secondary Sourcing



Umicore: 100% Sustainable Germanium supply

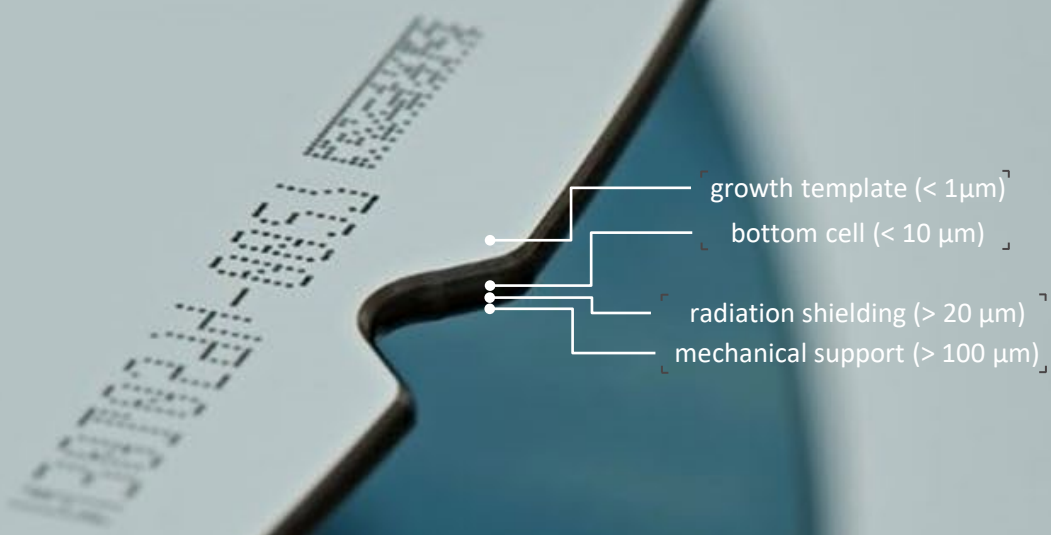


Umicore is the only Germanium producer with 100% sustainable germanium, and can additionally offer 100% recycled germanium

100% Sustainable Germanium GUARANTEED

100% Recycled Germanium AVAILABLE *

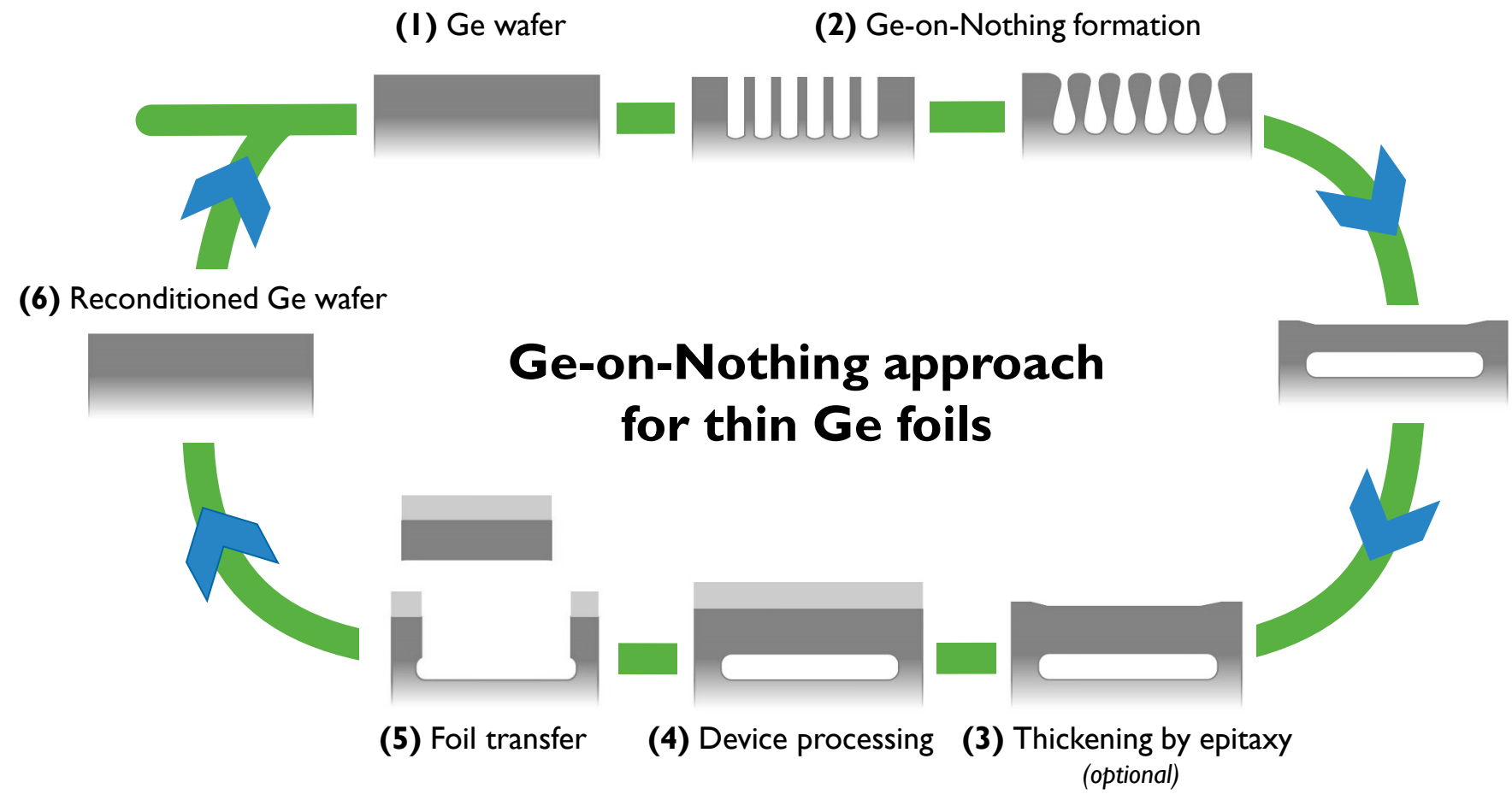
* Limited availability



GOING FOR...
LIGHTER
FLEXIBLE
CHEAPER
GE SUBSTRATES

Ge-on-Nothing approach

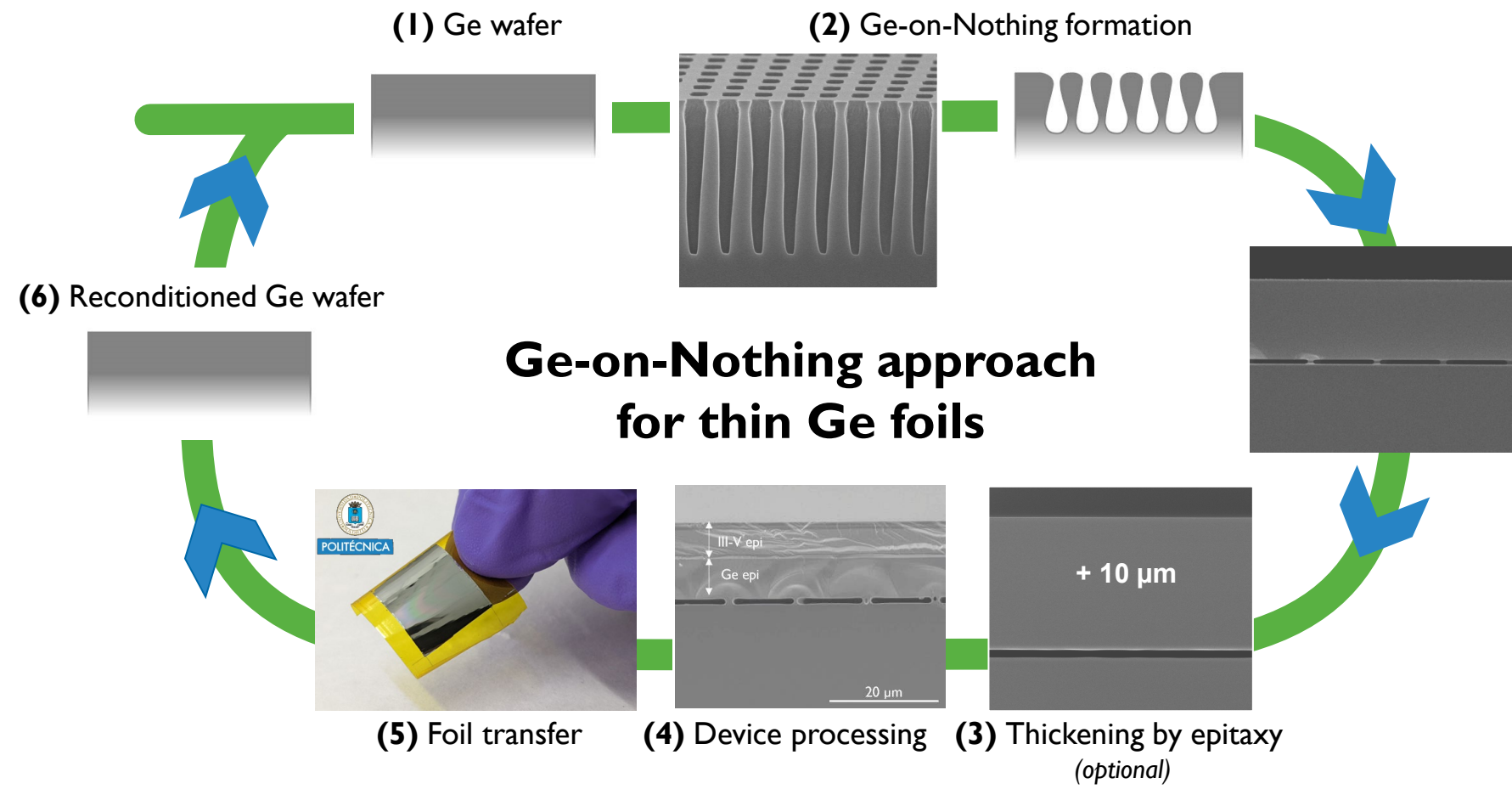
Technological testbed



Ge-on-Nothing approach for thin Ge foils

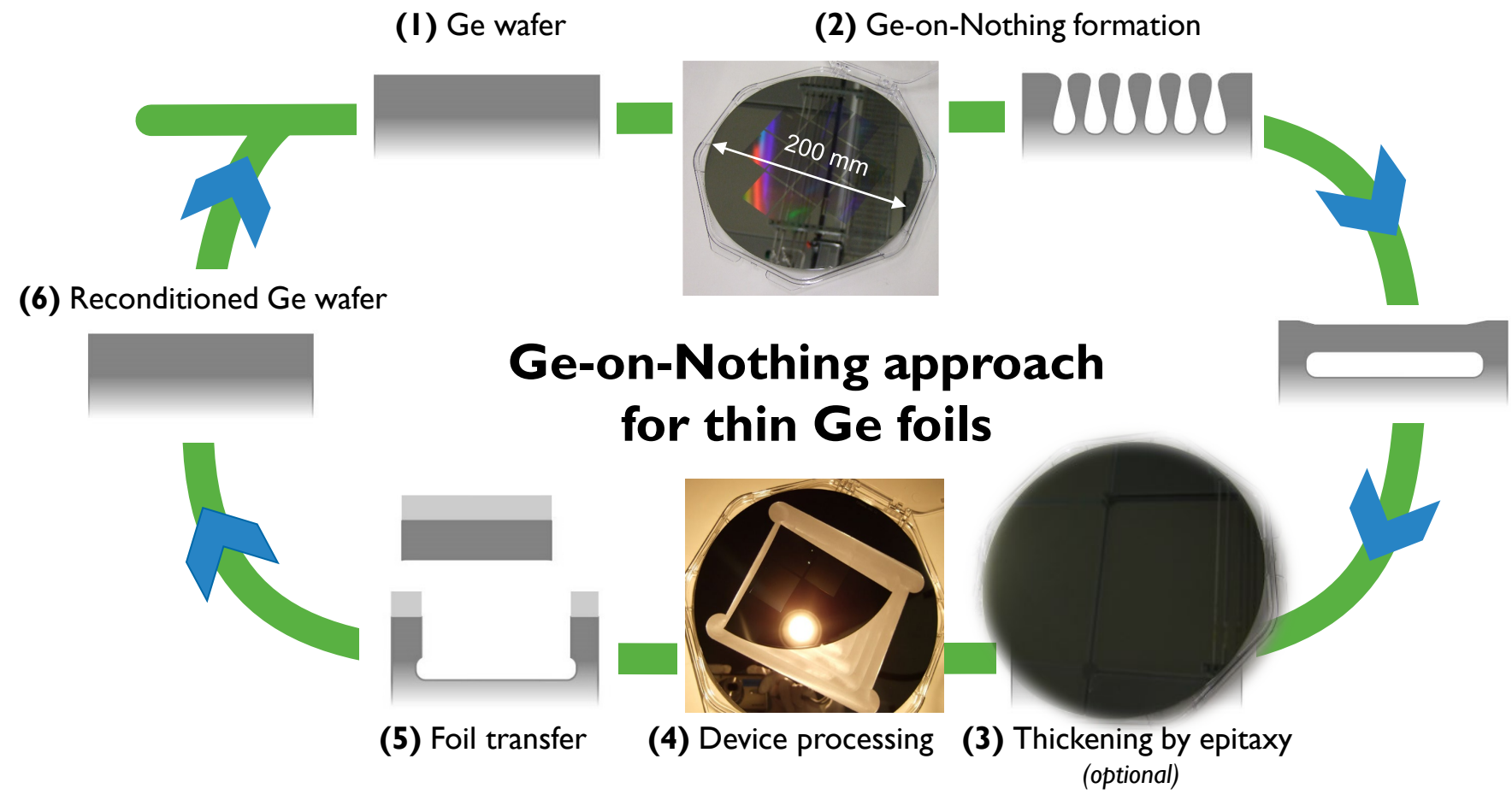
Ge-on-Nothing approach

Technological testbed



Ge-on-Nothing approach

Technological testbed on 8"



Ge-on-Nothing approach for thin Ge foils

Ge-on-Nothing approach

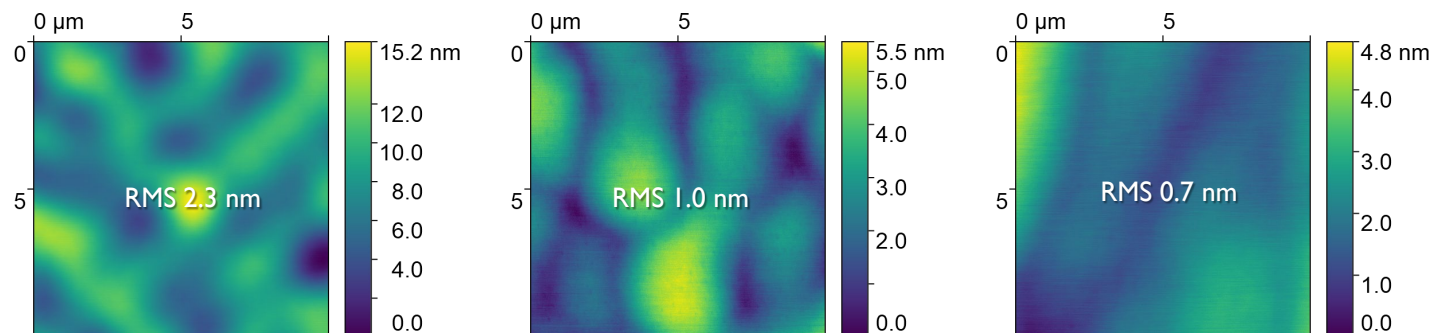
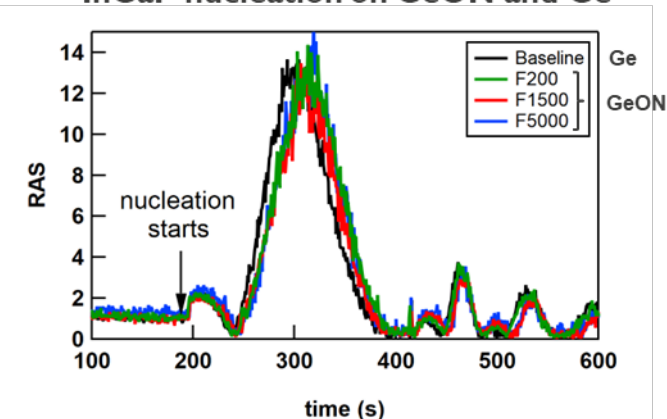
Technological testbed

- 6 deg. wafer **miscut** towards (111) is preserved
- **No dislocations**
- Minority-carrier **lifetime** of undoped 10- μm foils with a-Si:H surface passivation > 25 μs
- Virtually identical III-V **nucleation** on Ge vs. GeON
- HRXRD confirms layers are **lattice-matched**



POLITÉCNICA

InGaP nucleation on GeON and Ge



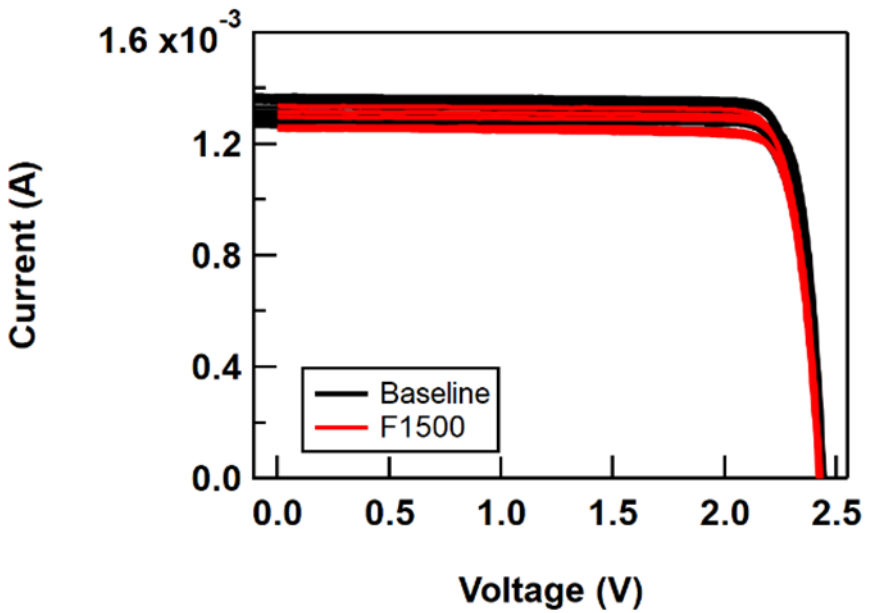
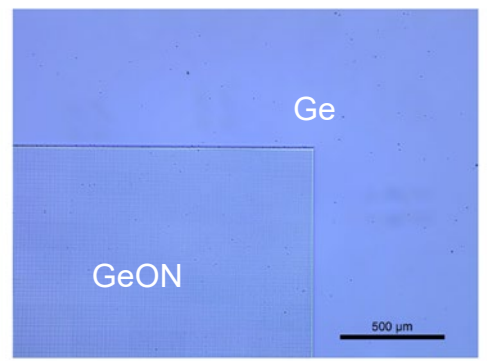
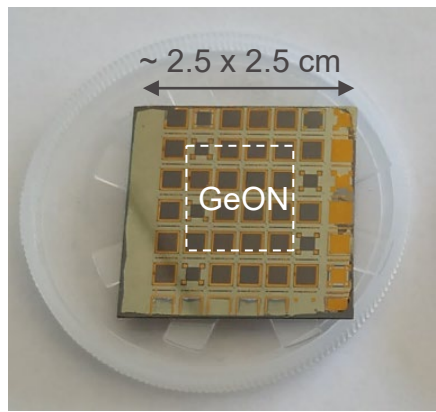
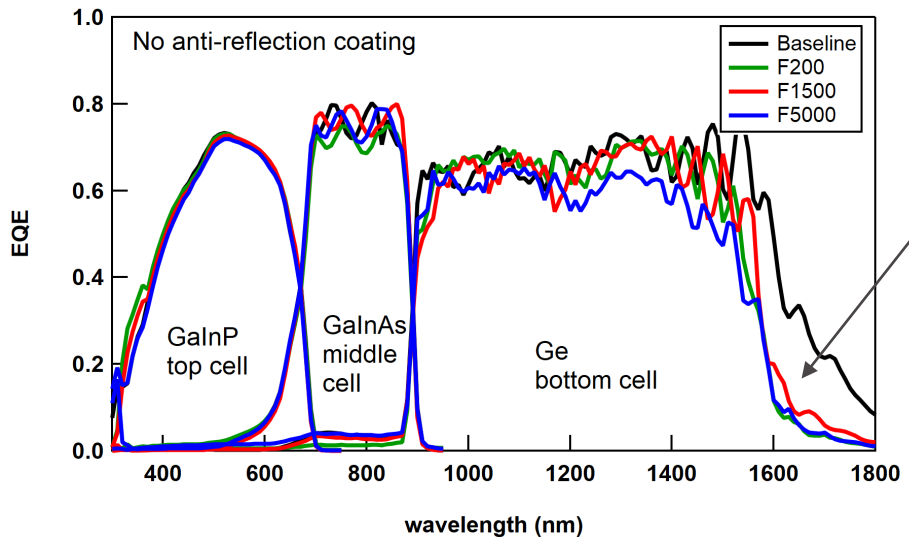
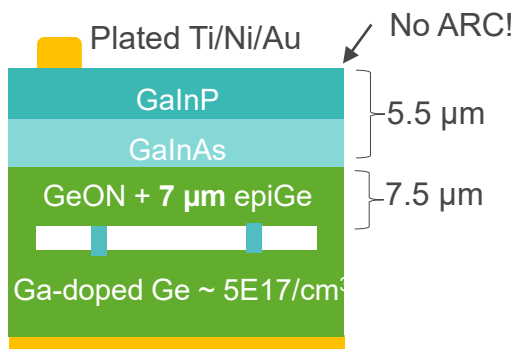
+ 0 μm epi

+ 2 μm epi

+ 10 μm epi

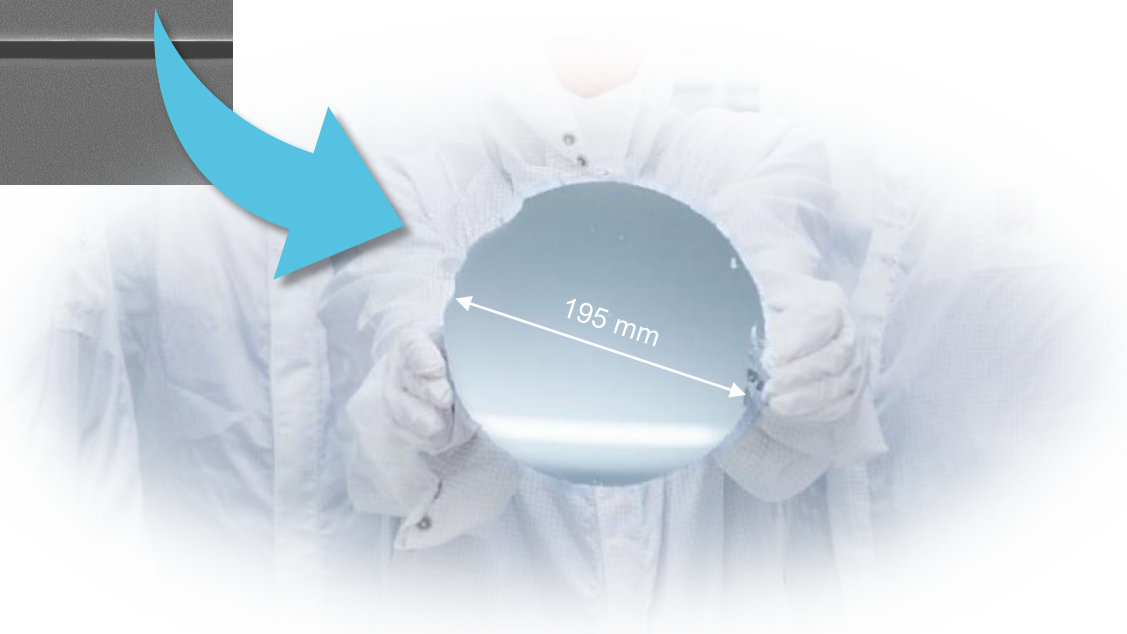
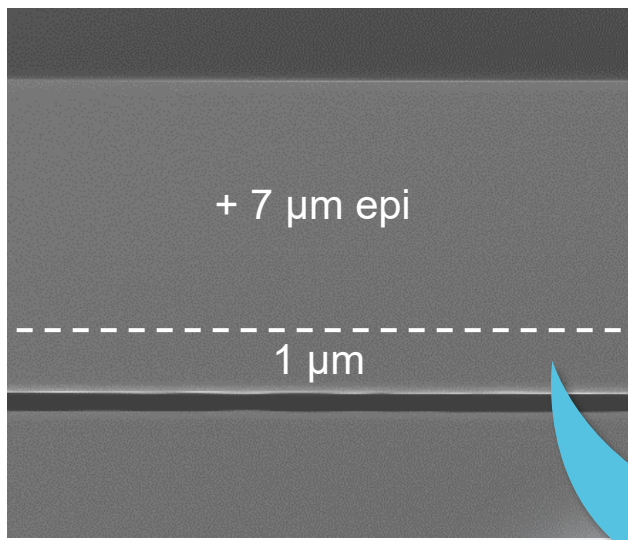
Ge-on-Nothing approach

Technological testbed



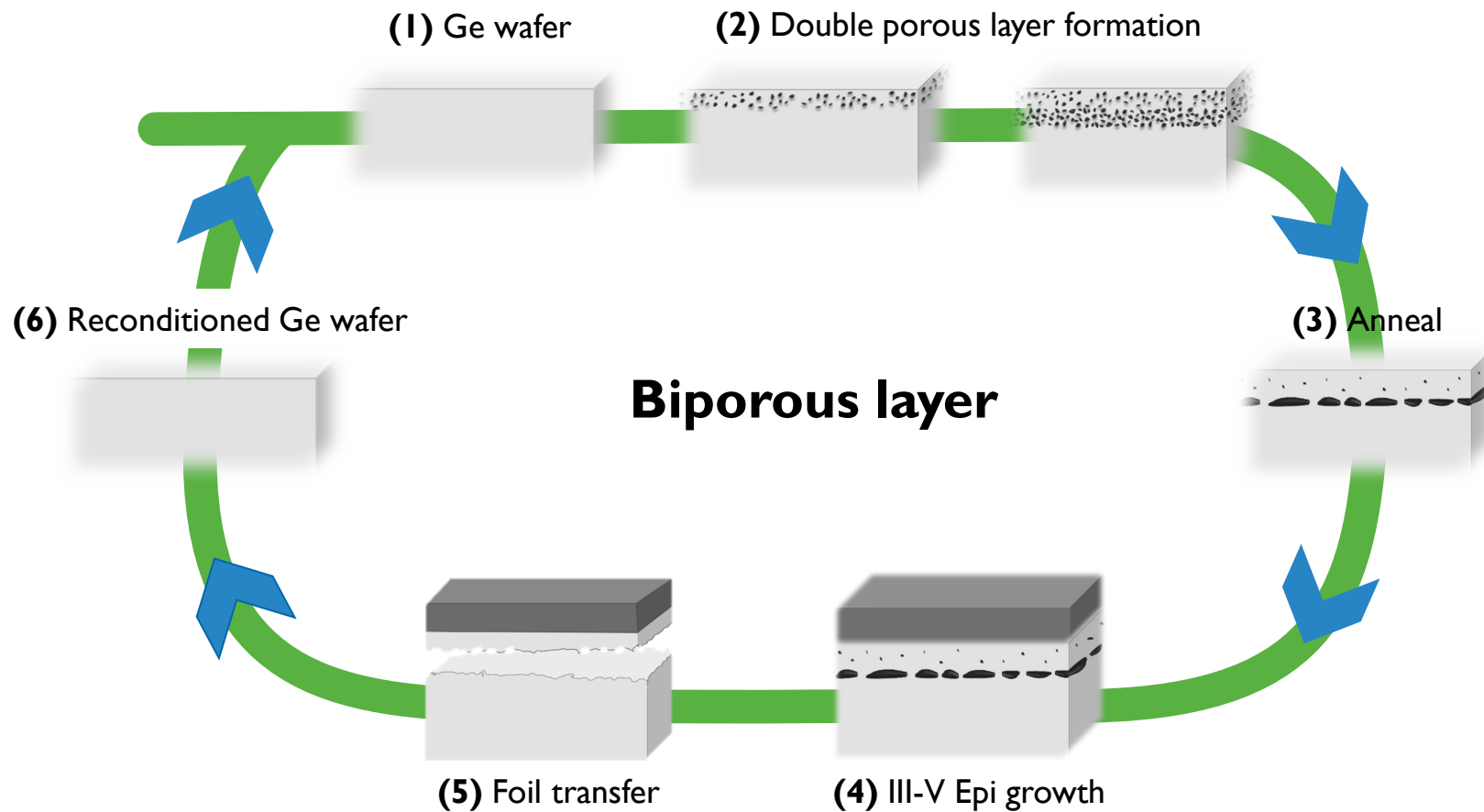
Ge-on-Nothing approach

Full wafer re-use demonstrated



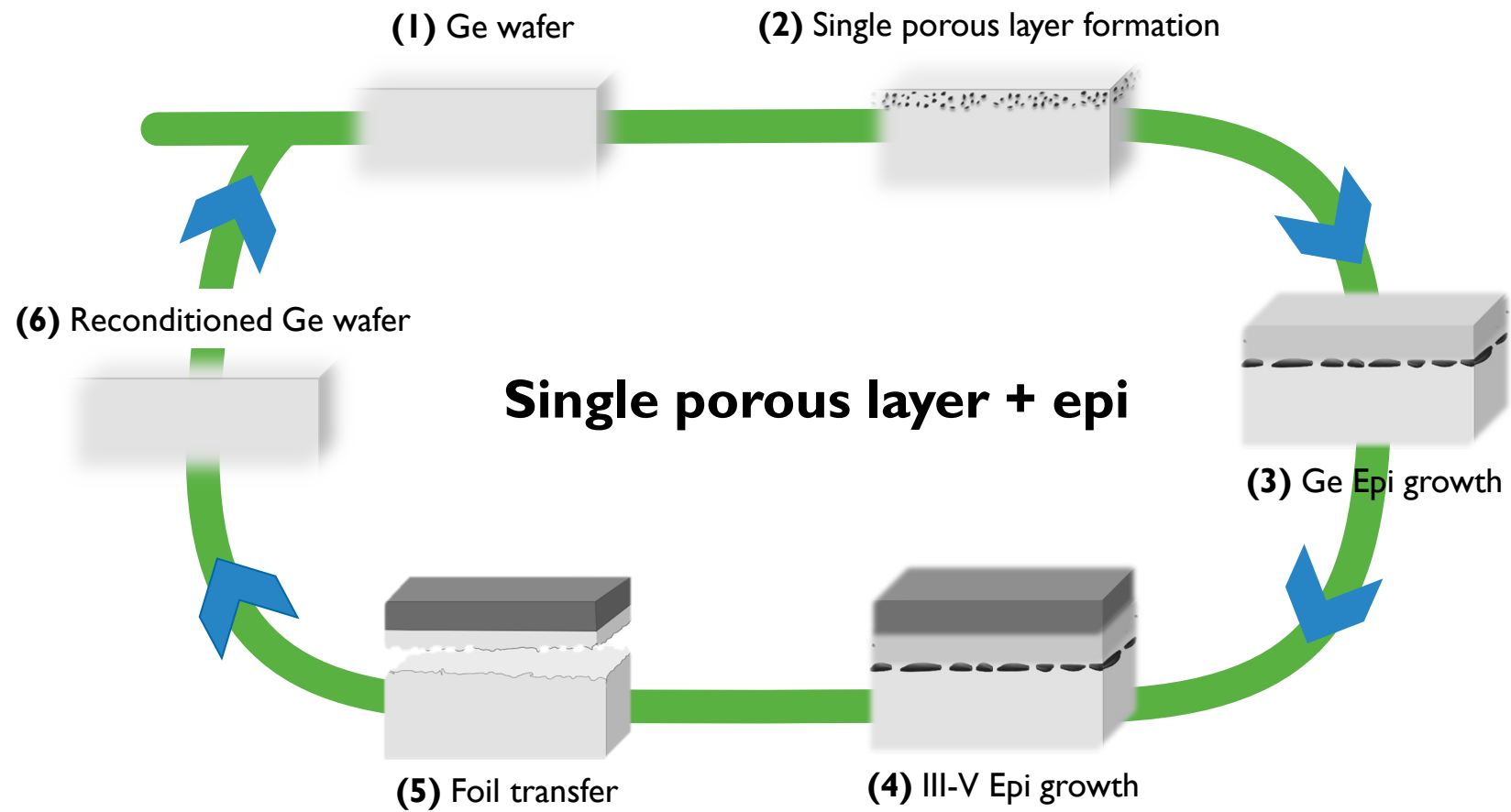
Electrochemical etching

Two approaches



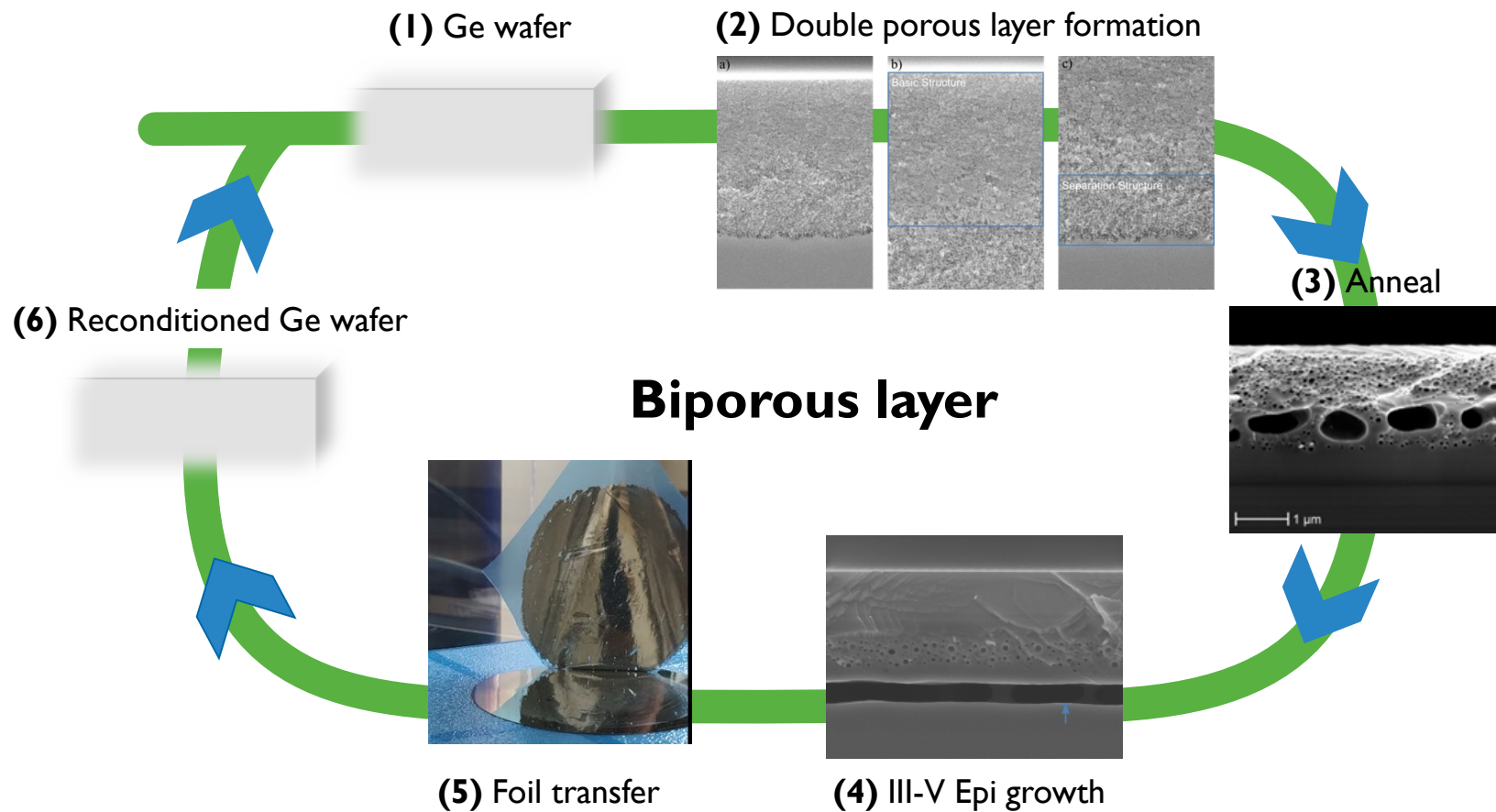
Electrochemical etching

Two approaches



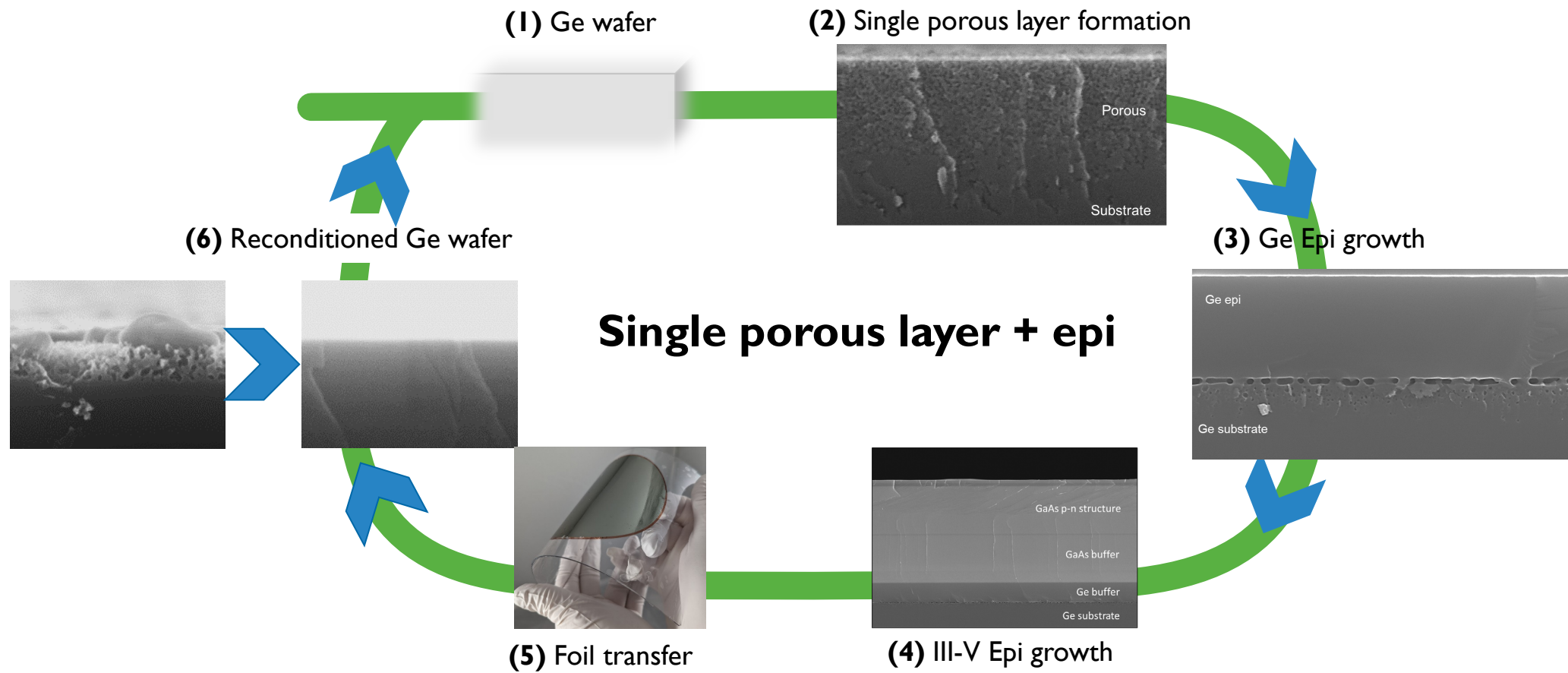
Electrochemical etching

Two approaches



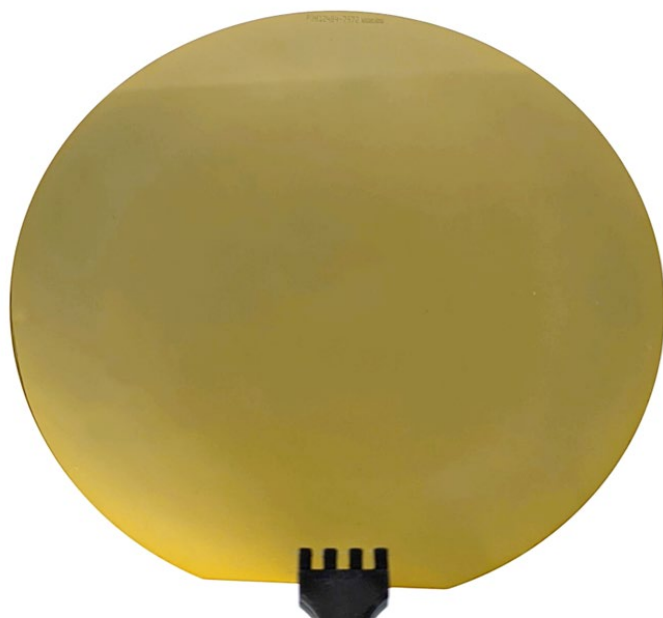
Electrochemical etching

Two approaches

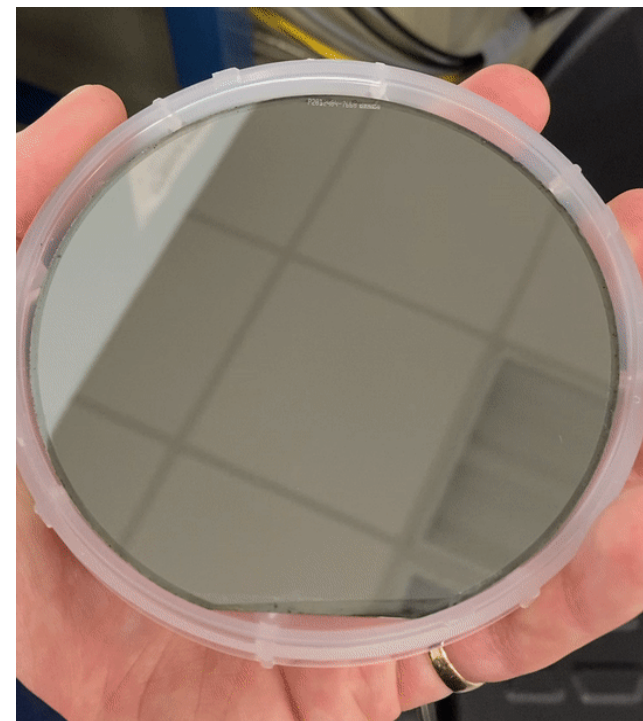


Electrochemical etching

Yields epi ready wafers...



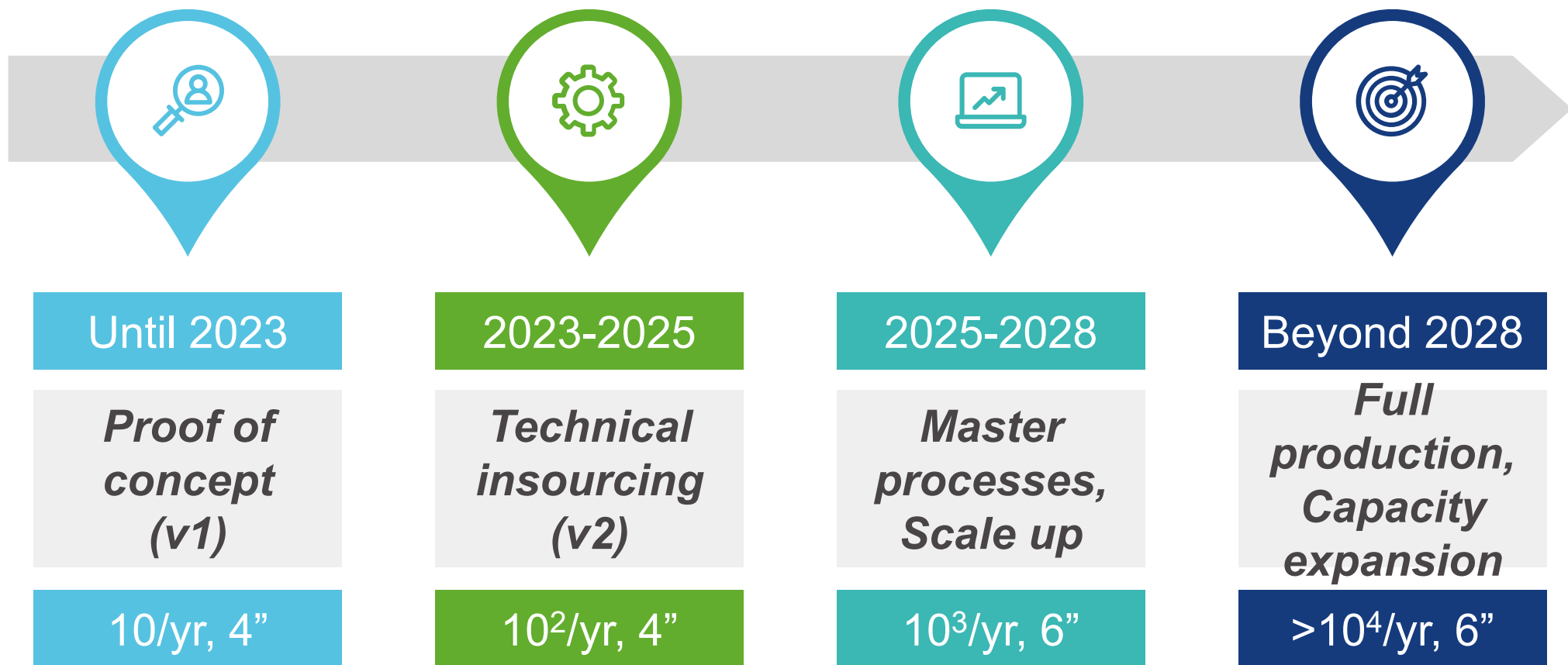
porous 4" wafer



Porous 4" wafer after Ge epitaxy

Engineered substrates – way forward

Upscaling to 6” and pilot fab @ Umicore Belgium



Connecting Life

